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Fig.1

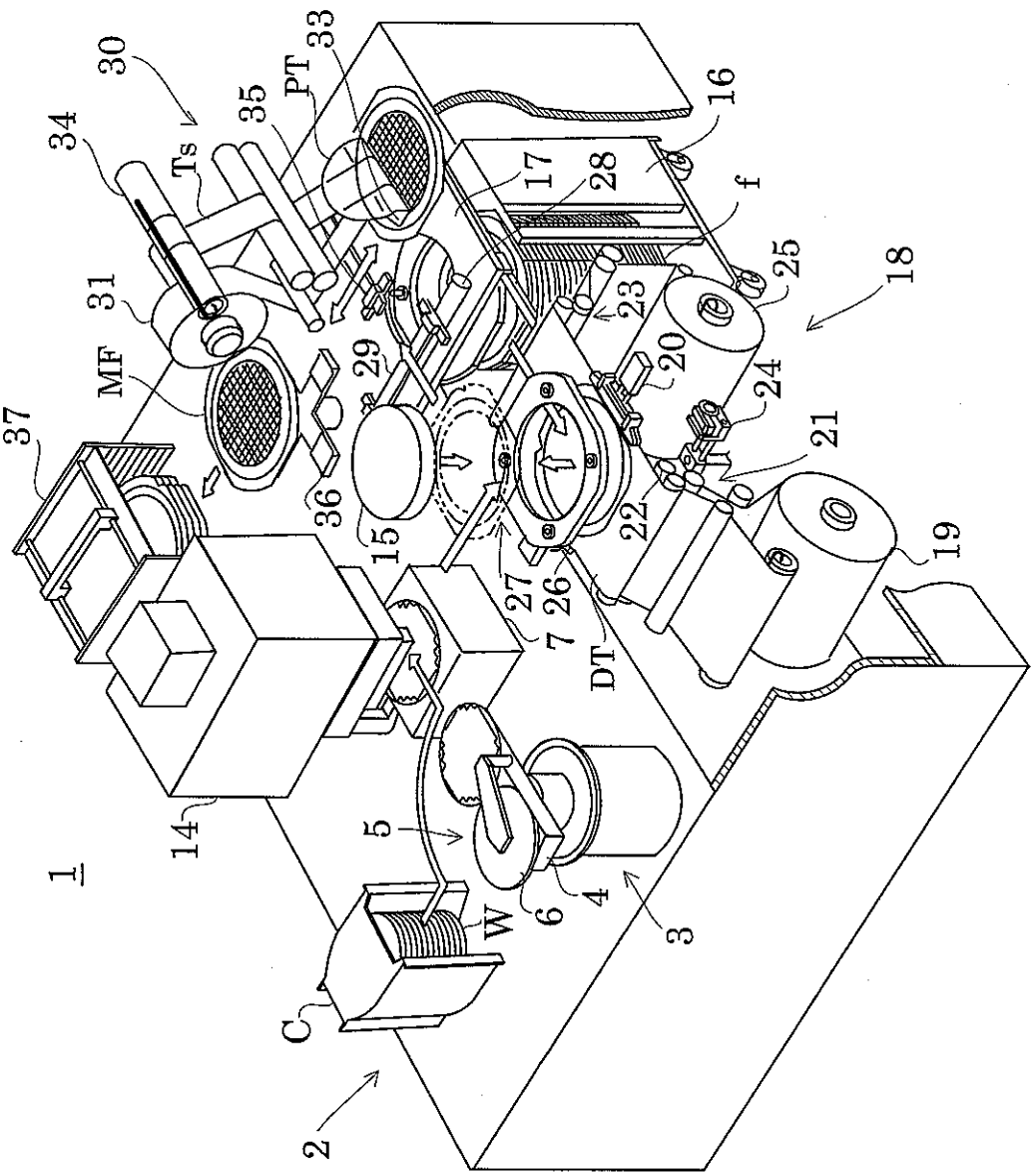


Fig.2

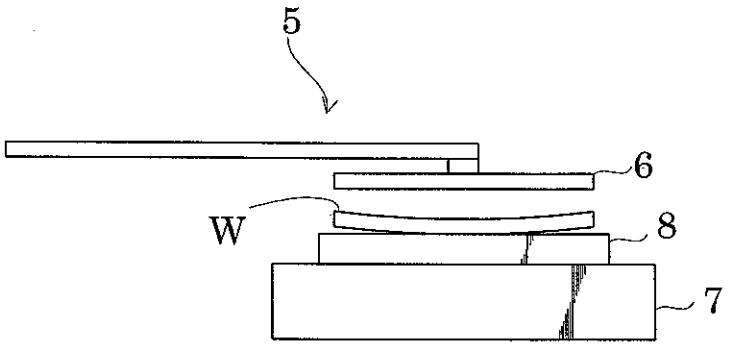


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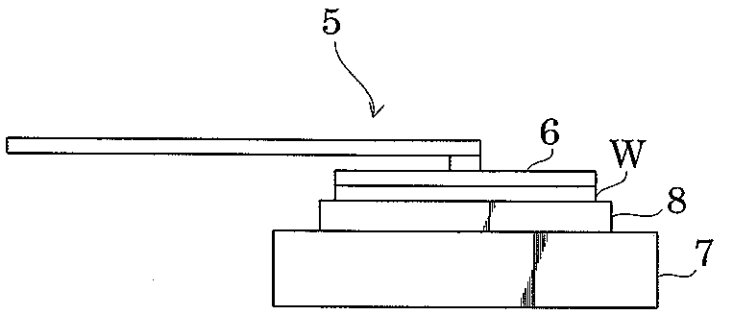


Fig.4

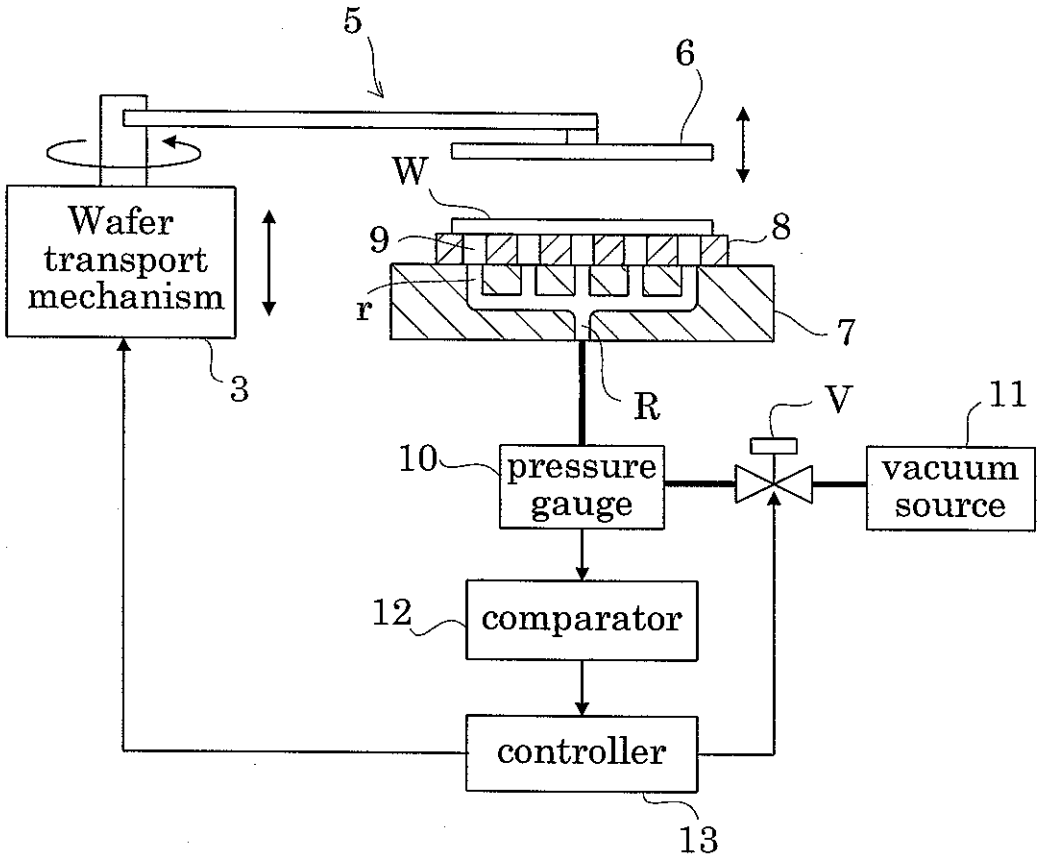

5
6
W
Wafer transport mechanism
9
8
r
7
3
R
V
11
10
pressure gauge
vacuum source
12
comparator
controller
13

Fig.5

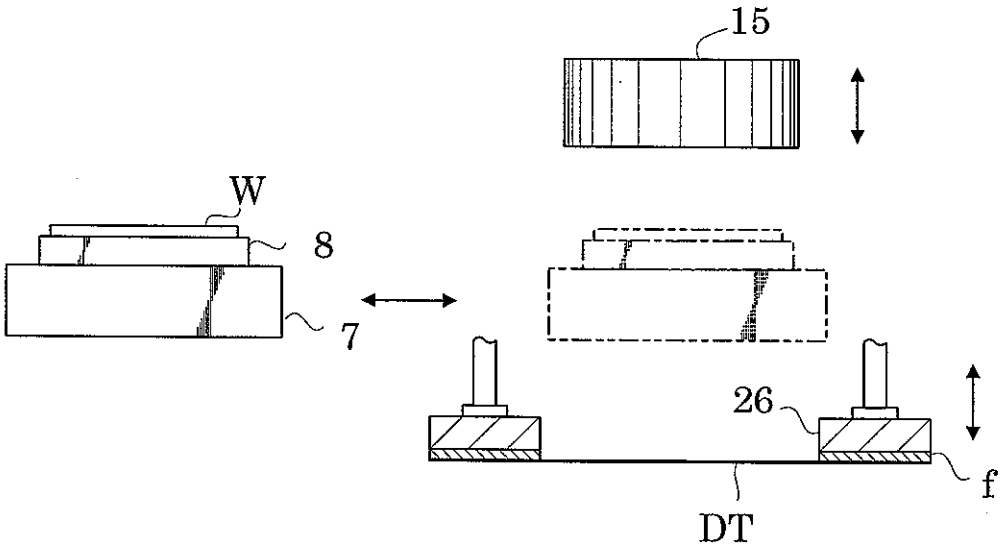

15
W
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26
f
DT

Fig.6

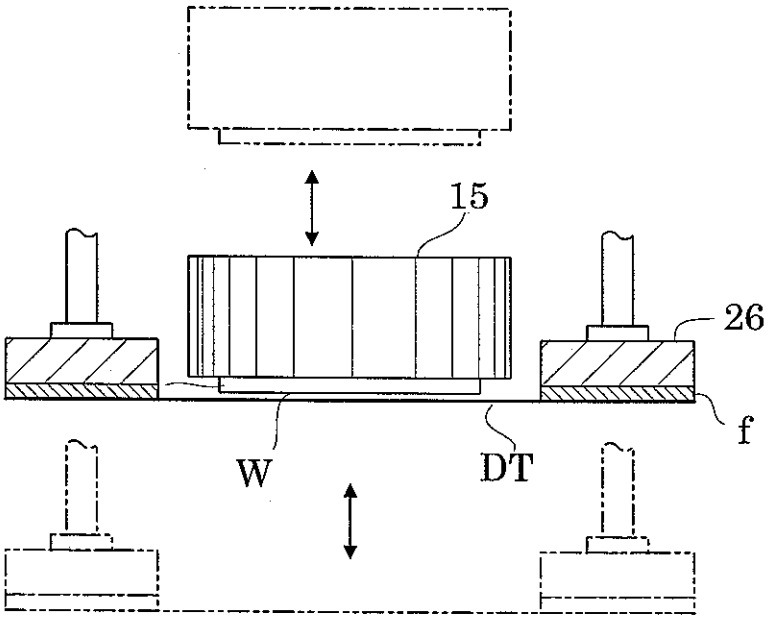
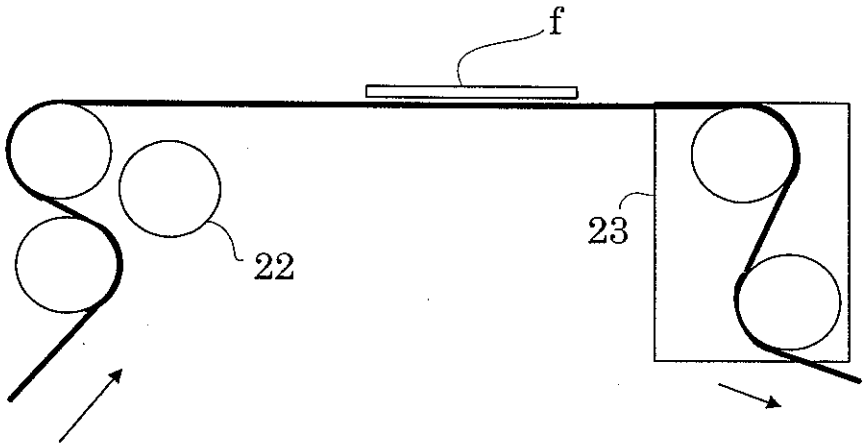


Fig.7



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Fig.8

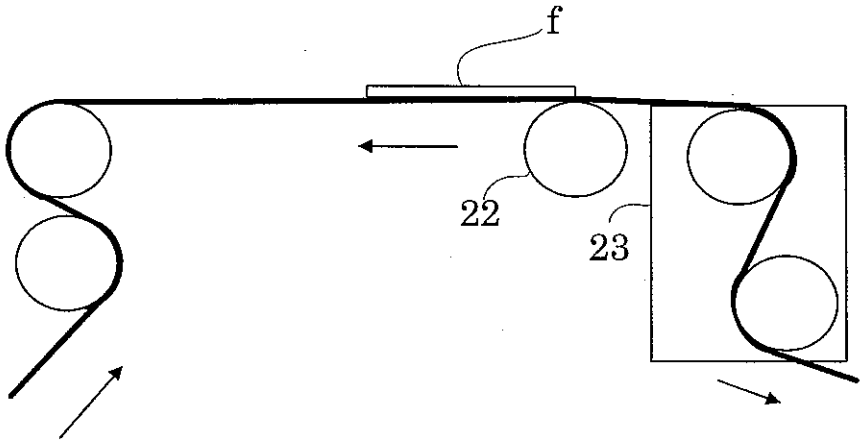
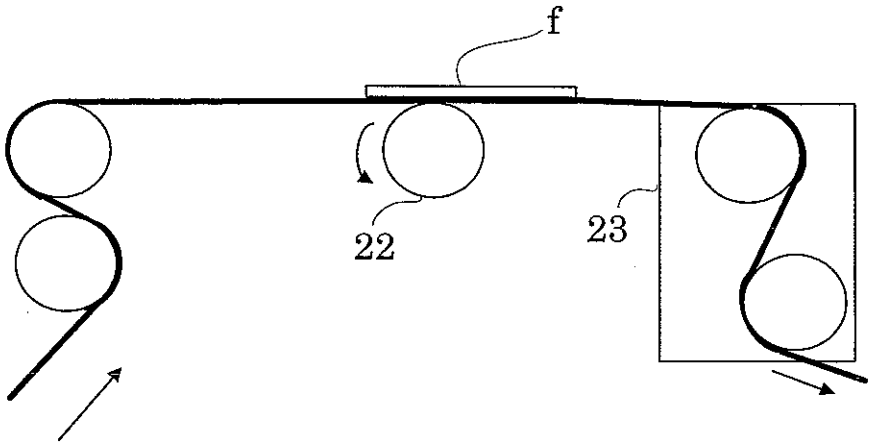


Fig.9



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Fig.10

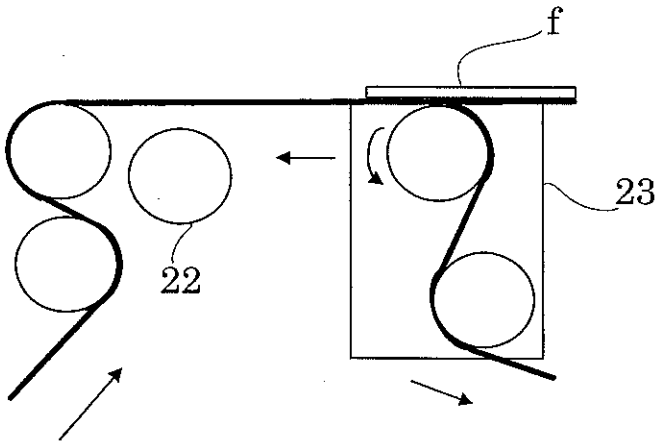
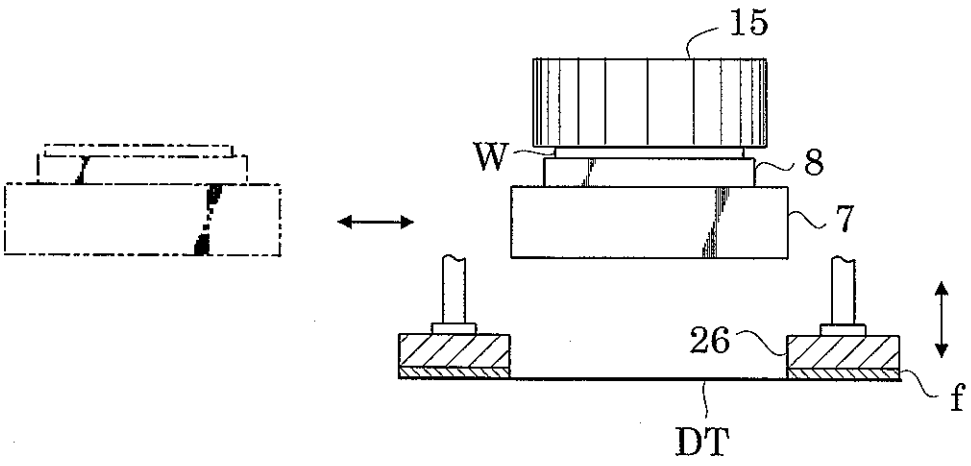


Fig.11



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Fig.12

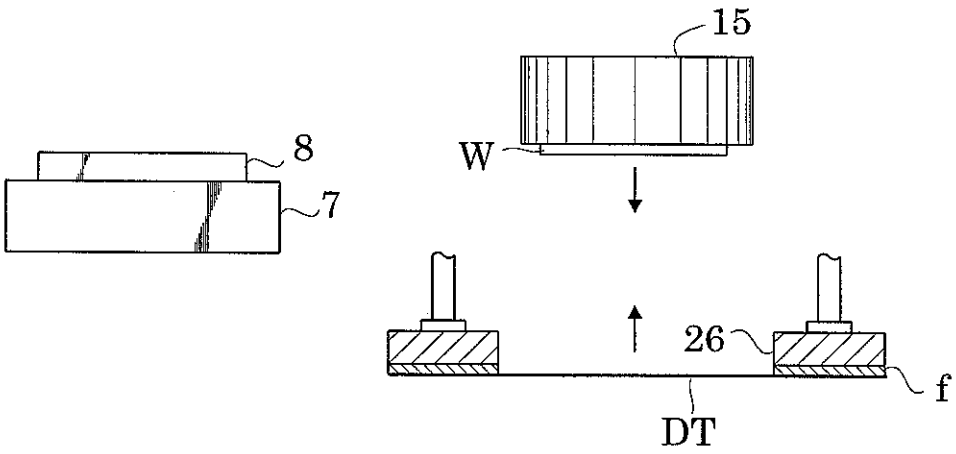
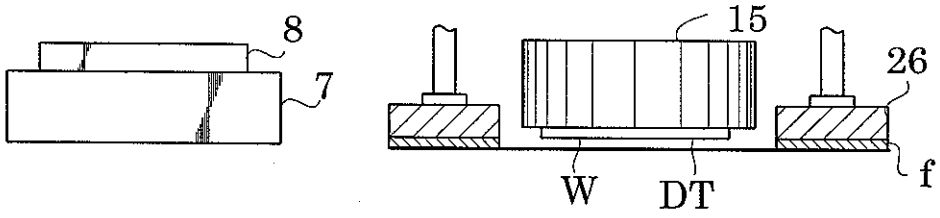


Fig.13



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Fig.14

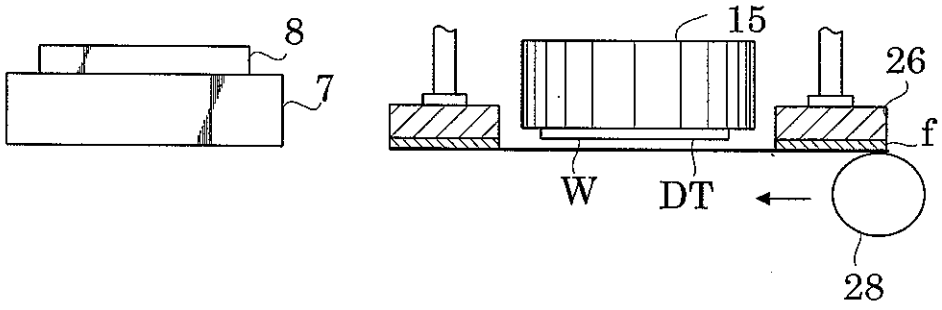
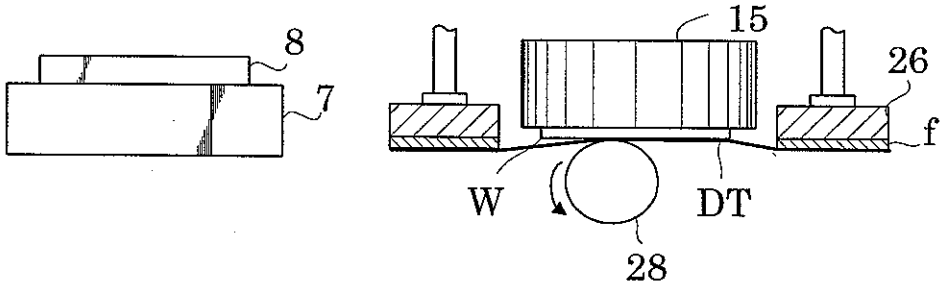


Fig.15



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Fig.16

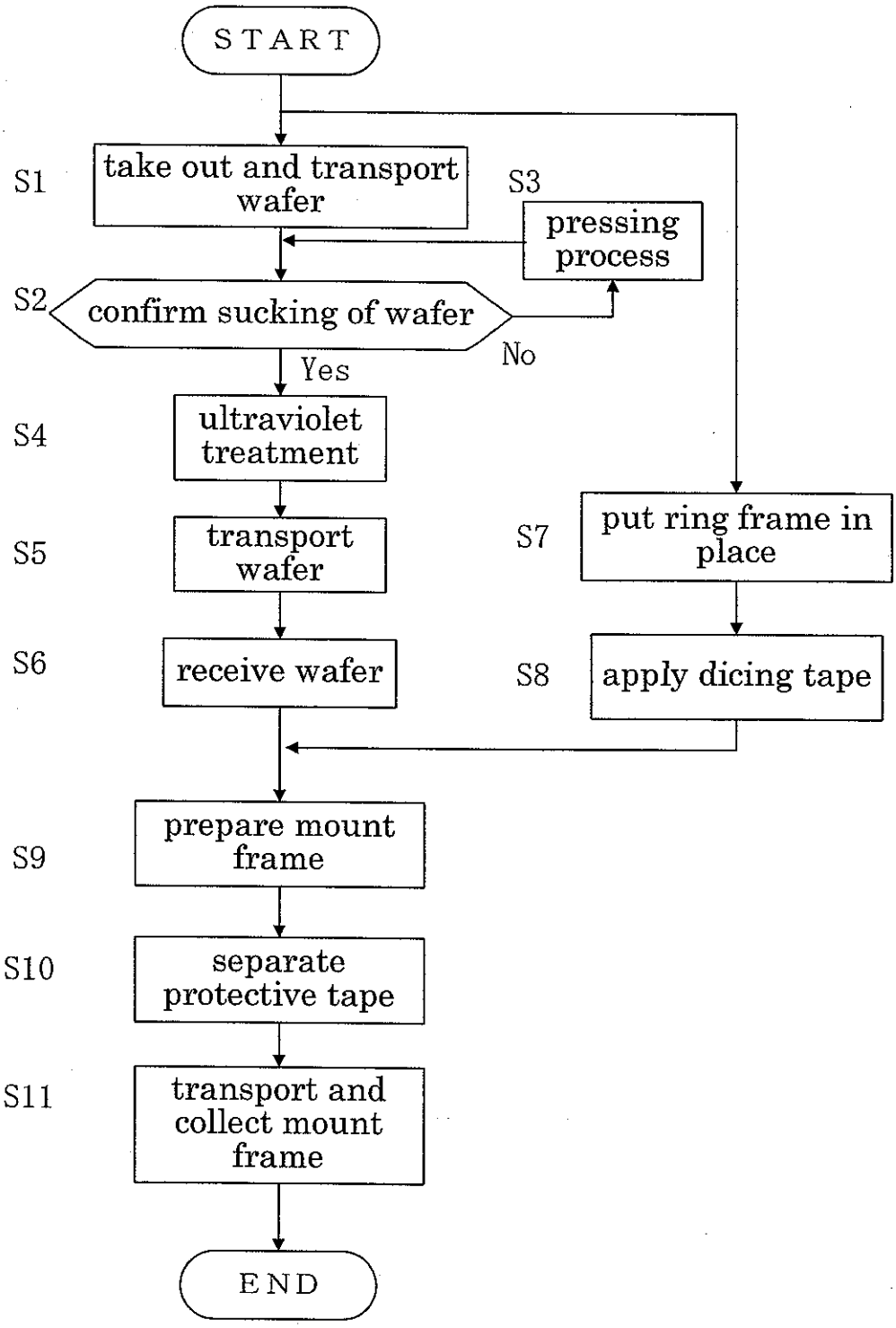


Fig.17

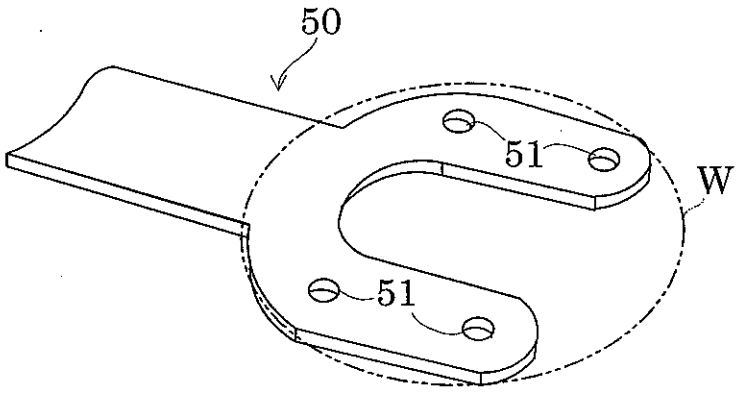


Fig.18

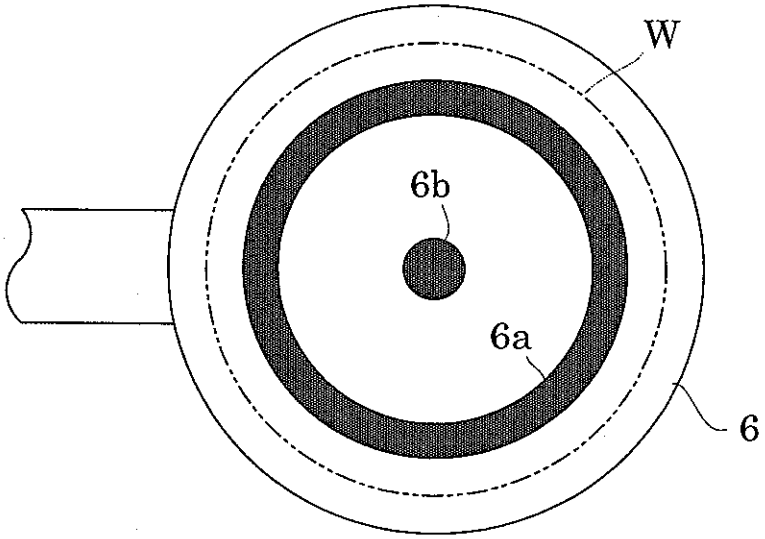


Fig.19

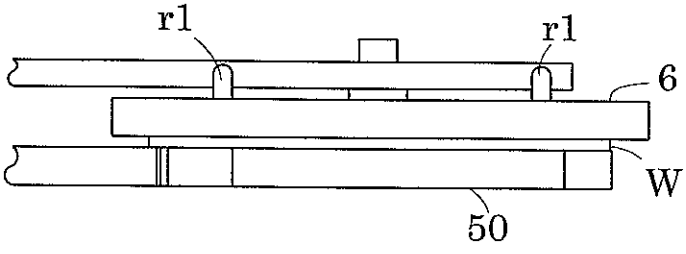


Fig.20

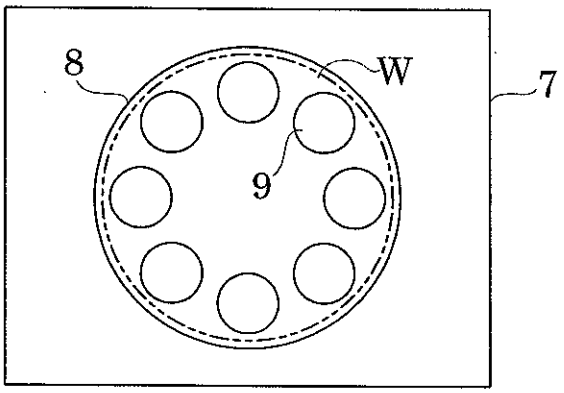
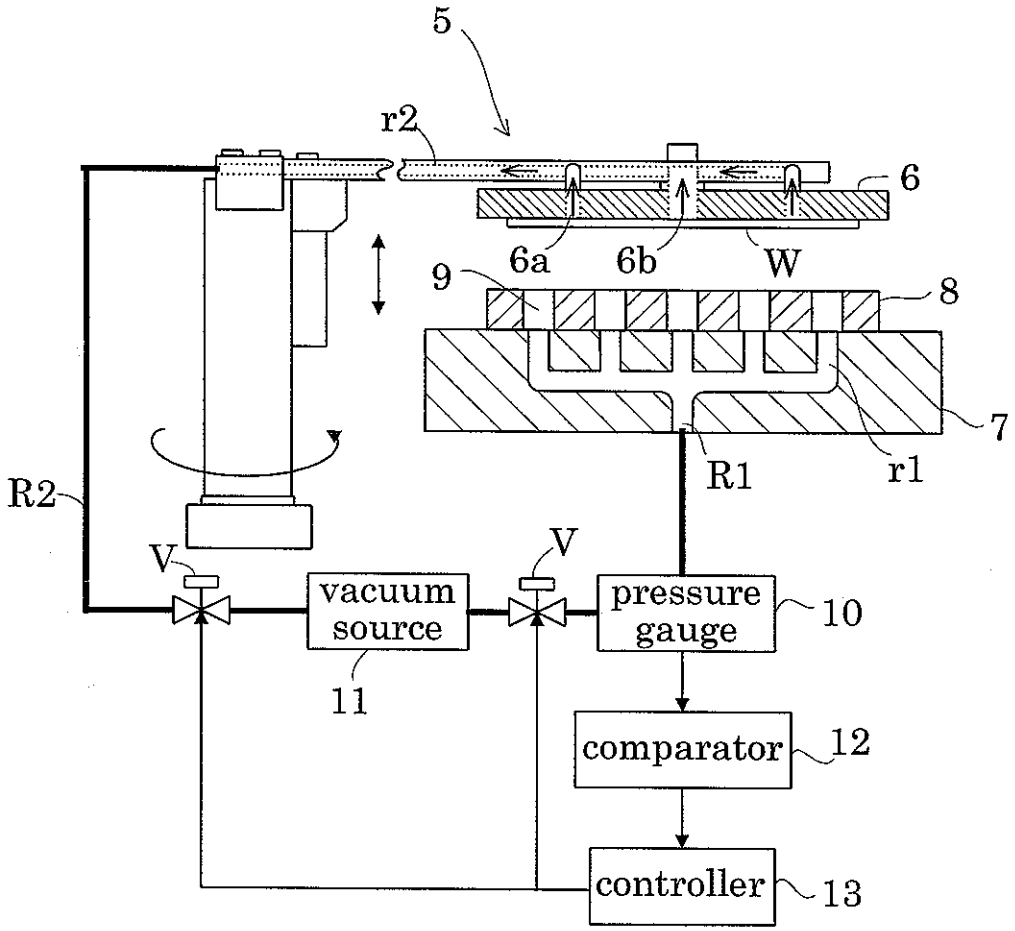

8
W
7
9

Fig.21


5
r2
6
6a
6b
W
9
8
7
R1
r1
R2
V
V
vacuum source
11
pressure gauge
10
comparator
12
controller
13